

Electronic Patent Application Fee Transmittal

Application Number:	10691108			
Filing Date:	22-Oct-2003			
Title of Invention:	DEVICE AND METHOD FOR ANISOTROPIC PLASMA ETCHING OF A SUBSTRATE, PARTICULARLY A SILICON ELEMENT			
First Named Inventor/Applicant Name:	Klaus Breitschwerdt			
Filer:	Gerard A. Messina/Tesha Ramos			
Attorney Docket Number:	10191/3399			
Filed as Large Entity				
Utility Filing Fees				
Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Basic Filing:				
Pages:				
Claims:				
Miscellaneous-Filing:				
Petition:				
Patent-Appeals-and-Interference:				
Post-Allowance-and-Post-Issuance:				
Utility Appl issue fee	1501	1	1400	1400
Publ. Fee- early, voluntary, or normal	1504	1	300	300

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Extension-of-Time:				
Miscellaneous:				
Total in USD (\$)				1700